

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Serial No.: Not Yet Received (Filed Contemporaneously with Application)
Filing Date: February 6, 2004
Applicant: Bruno Ullrich et al.
Entitled: METHOD AND APPARATUS FOR PRODUCING GALIUM
ARSENIDE AND SILICON COMPOSITES AND DEVICES
INCOPORATING SAME

Mail Stop Patent Application
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

INFORMATION DISCLOSURE STATEMENT UNDER 37 CFR §§ 1.97-1.98

As authorized and encouraged under 37 CFR §§ 1.97-1.98 and the provisions of MPEP §§ 609 and 707.05 (b), Applicant(s) submits herewith certain patent references, publications and/or other information which the Patent and Trademark Office may wish to consider in examining the above-identified patent application. The references and information are listed below and on attached form PTO-1449.

U.S. PATENTS/APPLICATIONS

U.S. PATENT/PUBLICATION NUMBER	INVENTOR(S)
US 2002/0030246 A1	Eisenbeiser et al.

FOREIGN PATENT DOCUMENTS

COUNTRY	PATENT NO.	INVENTOR(S)
NONE		

OTHER DOCUMENTS

1. ULLRICH et al., Preparation of Thin Film GaAs on Glass by Pulsed-Laser Deposition, Proceedings of SPIE, Vol. 4977 (2003).

A copy of each document is included for the express purpose of providing the Patent and Trademark Office with ample opportunity to evaluate the same and arrive at an independent assessment of the materiality of each, if any, to the examination of the above-identified application.

In reviewing the enclosed copies of the above documents, the Examiner is instructed to ignore any underscoring or highlighting which may have been done because such markings may or may not have any relationship to the subject matter of the above-identified application. The copies being submitted with this Information Disclosure Statement are the best copies available at this time.

The identification of any document herein is not intended to be, and should not be understood as being, an admission that each such document, in fact, constitutes "prior art" within the meaning of applicable law.

Applicant(s) respectfully requests that the documents cited herein be made of record in the normal manner and that such documents appear on the printed patent as being considered and made of record.

Respectfully submitted,

Date: February 6, 2004

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DATE OF DEPOSIT: February 6, 2004

**FORM PTO-1449 TO BE FILED WITH
INFORMATION DISCLOSURE STATEMENT**

U.S. Department of Commerce
Patent and Trademark Office

Atty. Docket No. BOW1335-046A Serial No.: Not Yet Rec'd

INFORMATION
DISCLOSURE STATEMENT
BY APPLICANTS

Bruno Ullrich et al.
Applicant

February 6, 2004
Filing Date

Group Art Unit

Examiner's name

U.S. PATENTS/APPLICATIONS

Examiner's Initial	Document Number	Date	Name	Class/Sub-class
	US 2002/0030246 A1	03/14/2002	Eisenbeiser et al.	257/629

FOREIGN PATENT DOCUMENTS

Examiner's Initial	Document Number	Date	Country/Name	Translation? yes/no
	NONE			

OTHER DOCUMENTS

1. ULLRICH et al., Preparation of Thin Film GaAs on Glass by Pulsed-Laser Deposition, Proceedings of SPIE, Vol. 4977 (2003).

Examiner	Date Considered
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Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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